

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	Hong-Jyh Li	Examiner:	Unassigned
Serial No.:	Unknown	Group Art Unit:	Unknown
Filed:	Herewith	Docket:	2004P51130US/I331.128.101
Title:	PLASMA ION IMPLANTATION SYSTEM		

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**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, it is respectfully requested that this Information Disclosure Statement be entered and the documents listed on attached form 1449 be considered by the Examiner and made of record. Any required copies of patents, publications or other documents are enclosed for the Examiner's review. Pursuant to the provisions of M.P.E.P. 609, Applicant further requests a copy of the 1449 form, marked as being considered and initialled by the Examiner, be returned with the next Official Communication.

Since this Information Disclosure Statement is being submitted within three months of filing national application; or date of entry of national application; or before the mailing date of the first Office Action on the merits, a fee has not been enclosed. However, if such fee is required, the Patent Office is hereby authorized to charge Deposit Account No. 500471 for fees as set forth under 37 C.F.R. 1.17(p).

**Information Disclosure Statement**

Applicant: Hong-Jyh Li

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Applicant respectfully requests consideration of these references during prosecution of the above-identified matter. The Examiner is invited to contact the Applicant's representative at the below-listed telephone number if there are any questions regarding this Communication or the tendered references.

Respectfully submitted,

Hong-Jyh Li,

By his attorneys,

DICKE, BILLIG & CZAJA, PLLC

Fifth Street Towers, Suite 2250

100 South Fifth Street

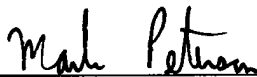
Minneapolis, MN 55402

Telephone: (612) 573-0120

Facsimile: (612) 573-2005

Dated: 4/1/2004

MAP:kle



Mark A. Peterson

Reg. No. 50,485

**CERTIFICATE UNDER 37 C.F.R. 1.10:**

"Express Mail" mailing label number: EV 365585517 US

Date of Deposit: April 1, 2004

The undersigned hereby certifies that this paper or papers, as described herein, are being deposited in the United States Postal Service "Express Mail Post Office to Addressee" service under 37 C.F.R. 1.10 on the date indicated above and is addressed to: Mail Stop Patent Application, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

By 

Name: Vernell Beal

<b>FORM PTO-1449</b>	Docket No.: 2004P51130US/I331.128.101	Serial No.:
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	Applicant: Hong-Jyh Li	
	Filing Date: Herewith	Group Art:

### U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Name	Class	Sub Class	Filing Date If Appropriate
AA	6,660,660	12/09/2003	Haukka et al.			
AB						
AC						
AD						
AE						
AF						
AG						
AH						
AI						
AJ						
AK						
AL						

### FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Class	Sub Class	Translated Yes No
AM						Yes
AN						Yes

### OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AP	Yankov, Rossen A. and Mändl, Stephan, "Plasma Immersion Ion Implantation for Silicon Processing", Ann. Phys. (Leipzig) 10 4, pp. 279-298, (2001).
AQ	Ensinger, W., "Semiconductor Processing by Plasma Immersion Ion Implantation", Materials Science and Engineering, pp. 258-268, (1998).

EXAMINER:

DATE CONSIDERED:

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.